

National Taiwan University of Science and Technology of Chemical Engineering

Application form of XPS

2023.8.19 rev

Instrument	X-Ray Photoelectron Spectroscopy (XPS)				
Full name of applicant		School & Department		Cell-Phone of applicant	
Advisor			E-Mail		
Appointment Date/Time	(Office only)		Operator	(Office only)	

Number of samples (< 6) : _____

Fabrication of samples (coating/substrate) : _____

Thickness : _____ (< 0.5 cm)

Magnetism : ☐ Yes (Fe, Co, Ni) ☐ No

Conductor : ☐ Yes ☐ No

Powder : ☐ Yes ☐ No

Elements to analyses : 1. _____ 2. _____ 3. _____ 4. _____ 5. _____ 6. _____ 7. _____ 8. _____

Surface clearing : ☐ Yes ☐ No (Low Ar⁺ energy , 10 sec)

Depth Profile : ☐ Yes ☐ No (High Ar⁺ energy) _only 2 samples

Etching Condition : _____ sec each time , _____ times in total (at most 300 sec each time)

or Etching for 300 sec : _____ times , Rescan , _____ times in total

To attend : ☐ Yes ☐ No

Keeping sample : ☐ Yes ☐ No (Sample will keep for two weeks)

Recommendation : Please label the front side or back side of the sample.

Advisor Signature: _____

Professor-in-charge Signature (E2-307 Lu-Sheng Hong): _____

實際使用時間:

(由操作員填寫)